



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Art Unit: 2815  
Examiner: Mr. William F. Kraig

In re PATENT APPLICATION of:

Applicant	:	Akira TAKAHASHI	)	
			)	
Serial No.	:	10/798,482	)	AMENDMENT
			)	AFTER
Filed	:	March 12, 2004	)	<u>FINAL REJECTION</u>
			)	
For	:	DRY ETCHING METHOD FOR	)	
		SEMICONDUCTOR DEVICE	)	
			)	
Attorney Ref.	:	OKI 414	)	
			)	

August 7, 2007

Director of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is responsive to the Office Action of February 8, 2007, the period for reply to which is being extended to expire on August 8, 2007 by a Petition filed concurrently herewith. A Request for Continued Examination (RCE) is also being filed concurrently.

A fee of \$ 1810 is also being submitted concurrently. Should this remittance be accidentally missing, however, or should any additional fees be needed, the Director may charge such fees to our Deposit Account number 18-0002.

Please amend the above-identified application as specified on the following pages, and then reconsider the application in view of the Remarks that are presented thereafter.